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Respectfully submitted,



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PTO/SB/08a (08-03)

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Substitute for form 1449A/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use as many sheets as necessary)

Sheet 1

of 2

Application Number	10/768,724
Filing Date	JANUARY 30, 2004
First Named Inventor	TAKEAKI EBIHARA, ET AL.
Group Art Unit	UNKNOWN
Examiner Name	UNKNOWN
Attorney Docket Number	AMAT/8736/DSM/BCVD/JW
Submission Date	April 30, 2004

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
	A1	US-6,627,933 B2	09/30/2003	Juengling	
	A2	US-6,611,316 B2	08/26/2003	Sewell	
	A3	US-6,573,030 B1	06/03/2003	Fairbairn, et al.	
	A4	US-6,541,397 B1	04/01/2003	Bencher	
	A5	US-6,514,667 B2	02/04/2003	Angelopoulos, et al.	
	A6	US-6,511,791 B1	01/28/2003	Bukofsky, et al.	
	A7	US-6,483,571 B1	11/19/2002	Shiraishi	
	A8	US-6,458,516 B1	10/01/2002	Ye, et al.	
	A9	US-6,423,384 B1	07/23/2002	Khazeni, et al.	
	A10	US-6,403,291 B1	05/29/2001	Bula, et al.	
	A11	US-6,331,380 B1	12/18/2001	Ye, et al.	
	A12	US-6,316,167 B1	11/13/2001	Angelopoulos, et al.	
	A13	US-6,238,850 B1	05/29/2001	Bula, et al.	
	A14	US-6,184,572 B1	02/06/2001	Mountsier, et al.	
	A15	US-6,143,476	11/07/2000	Ye, et al.	
	A16	US-6,080,529	06/27/2000	Ye, et al.	
	A17	US-6,042,993	03/28/2000	Leuschner, et al.	
	A18	US-5,830,332	11/03/1998	Babich, et al.	
	A19	US-2004/0023475 A1	02/05/2004	Bonser, et al.	
	A20	US-2003/0186477 A1	10/02/2003	Bencher	
	A21	US-2003/0091938 A1	05/15/2003	Fairbairn, et al.	
	A22	US-2002/0001778 A1	01/03/2002	Latchford, et al.	
	A23				
	A24				
	A25				
	A26				
	A27				

Examiner

Date Considered

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This collection of information is required by 37 CFR 1.97 and 1.98. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 2 hours to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450. If you need assistance in completing the form, call 1-800-PTO-9199 (1-800-786-9199) and select option 2.

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Substitute for form 1449B/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(Use as many sheets as necessary)</i>				Application Number	10/768,724
				Filing Date	JANUARY 30, 2004
				First Named Inventor	TAKEAKI EBIHARA, ET AL.
				Group Art Unit	UNKNOWN
				Examiner Name	UNKNOWN
				Attorney Docket Number	AMAT/8736/DSM/BCVD/JW
Sheet	2	of	2	Submission Date	April <u>30</u> , 2004

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T ²
	B1	CANON USA, "Canon Extends Lithography Roadmap: Presents Resolution Capabilities Beyond k1 or 0.25 at BACUS" http://www.usa.canon.com/templatedata/pressrelease/20030904_photomask.html (2 pages), press release dated September 4, 2003.	
	B2	SALEEM H. ZAIDI, ET AL. "Nonlinear Processes to Extend Interferometric Lithography" SPIE Conference on Emerging Lithographic Technologies III, March 1999, SPIE Vol. 3676, pp. 371-378.	
	B3	BRIAN TYRRELL, ET AL. "Investigation of the Physical and Practical Limits of Dense-Only Phase Shift Lithography for Circuit Feature Definition" J. Microlith., Microfab., Microsyst., Vol. 1 No. 3, October 2002.	
	B4	TAKEAKI EBIHARA, ET AL. "Beyond k ₁ =0.25 lithography: 70nm L/S patterning using KrF scanners" Proc. SPIE 5256-105, 10 pages, December 2003.	
	B5	TAKEAKI EBIHARA, ET AL. "150nm Dense/Isolated Contact Hole Study with Canon IDEAL Technique" 21 st Annual BACUS Symposium on Photomask Technology, Proceeding of SPIE Vol. 4562, April 2002, pp. 1068-1076.	

Examiner	Date Considered
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. 1 Applicant's unique citation designation number (optional). 2 Applicant is to place a check mark here if English language Translation is attached.

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